Attorney Docket No.: 99CON114P

## IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of: Liu, et al.

Serial No.: 09/575,055

Filed: May 19, 2000

For: Method for Selective Fabrication of High Capacitance Density Areas in a

Low Dielectric Constant Material

Art Unit: 2818

Examiner: Luu, Chuong A.

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## **RESPONSE TO FINAL OFFICE ACTION**

Mail Stop AF Honorable Commissioner for Patents P.O. Box 1450 Alexandria, VA 22313-1450 OK, to be entered.

Dear Sir/Madam:

This is in response to the *Final Office Action* dated July 26, 2005 in the abovereferenced patent application. Please enter and consider the following remarks.